

PTO-1449 REPRODUCED

ATTORNEY DOCKET NO.  
3194.1026-002APPLICATION NO.  
10/683,904OIP INFORMATION DISCLOSURE CITATION  
IN AN APPLICATIONFIRST NAMED INVENTOR  
Daniel Alvarez, Jr.FILING DATE  
October 10, 2003

NOV 24 2004

November 11, 2004

(Use several sheets if necessary)

EXAMINER  
Bibi Sharidan CarrilloCONFIRMATION NO.  
3090GROUP  
1746

## U.S. PATENT DOCUMENTS

EXAM- INER INITIAL	REF. NO.	DOCUMENT NUMBER Number-Kind Code (if known)	ISSUE DATE / PUBLICATION DATE MM-DD-YYYY	NAME OF PATENTEE OR APPLICANT OF CITED DOCUMENT
<i>hsc</i>	AA	5,013,335	05-07-1991	Marcus
<i>hsc</i>	AB	5,160,512	11-03-1992	Talu
	AC	<del>5,351,415A</del>	<del>10-04-1994</del>	<del>Brooks et al.</del> } <i>previous</i>
<i>hsc</i>	AD	5,540,757	07-30-1996	Jordan, Sr.
	AE	<del>5,602,683A</del>	<del>02-11-1997</del>	<del>Straaijer et al.</del> } <i>cited on 892</i>
<i>hsc</i>	AF	5,676,737	10-14-1997	Whitlock
<i>hsc</i>	AG	5,883,738A	11-10-1998	Carrea et al.
	AH	<del>5,846,338A</del>	<del>12-08-1998</del>	<del>Bonora et al.</del>
<i>hsc</i>	AI	5,869,401A	02-09-1999	Brunemeier et al.
<i>hsc</i>	AJ	5,968,232	10-19-1999	Whitlock
<i>hsc</i>	AK	6,221,132 B1	04-24-2001	Dong et al.
	AA2	<del>6,391,090B1</del>	<del>05-21-2002</del>	<del>Alvarez, Jr. et al.</del>
	AB2	<del>6,427,703B1</del>	<del>08-06-2002</del>	<del>Somekh</del>
<i>hsc</i>	AC2	6,461,410	10-08-2002	Abe et al.
	AD2	<del>6,638,341B1</del>	<del>10-28-2003</del>	<del>Speigelman et al.</del> }
	AE2	<del>6,724,460B2</del>	<del>04-20-2004</del>	<del>Van Schaik et al.</del>
<i>hsc</i>	AF2	US2002/0018189A1	02-14-2002	Mulkens et al.
	AG2	<del>US2003/0096193A1</del>	<del>05-22-2003</del>	<del>Van Schaik et al.</del>
<i>hsc</i>	AH2	US2002/0192129A1	12-19-2002	Shamouilian et al.

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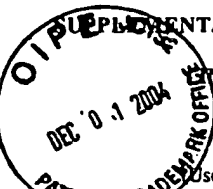
Use several sheets if necessary)

## OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)

	AR	<del>Handbook of Semiconductor Wafer Cleaning Technology, Science, Technology, and Applications, Werner Kern Associates, eds., (NJ: Noyes Publications) pp. 88-89 (1993).</del> <i>Previously cited on 892.</i>
<i>BSC</i>	AS	Veillerot, Marc, "A Method for Measuring AMC Concentrations Inside Wafer Containers," Materials Integrity Management Symposium 2003.
<i>BSC</i>	AT	Martin, Ray <i>et al.</i> , "Status of Microenvironment Gas Purge in the Semiconductor Industry," Materials Integrity Management Symposium 2003.
<i>BSC</i>	AU	Davidson, John, "The Expanding Role of Bare Reticle Stockers in Photolithography," Materials Integrity Management Symposium 2003.
<i>BSC</i>	AV	Veillerot <i>et al.</i> , "Organic Contamination: Purge Gas Impacts in Plastic Storage Boxes," Solid State Phenomena, vol. 92, pp. 105-108 (2003).
<i>BSC</i>	AW	Veillerot <i>et al.</i> , "Testing the use of purge gas in wafer storage and transport containers," [online] 1997-2003 [retrieved 2004-11-10]. Retrieved from the Internet <URL: <a href="http://www.micromagazine.com/archive/03/08/veillerot.html">http://www.micromagazine.com/archive/03/08/veillerot.html</a>
<i>40</i>	AX	Pearlstein <i>et al.</i> , "Evaluating electronics-grade gas-line purging requirements," [online] March, 2001 [retrieved 2004-10-18]. Retrieved from the Internet <URL: <a href="http://sst.pennnet.com/Articles/Article_Display.cfm?Section=ARCHI&amp;ARTICLE_ID=95491&amp;VERSION_NUM=1&amp;p=5">http://sst.pennnet.com/Articles/Article_Display.cfm?Section=ARCHI&amp;ARTICLE_ID=95491&amp;VERSION_NUM=1&amp;p=5</a>

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PTO-1449 REPRODUCED		ATTORNEY DOCKET NO. 3194.1026-002		APPLICATION NO. 10/683,904	
 SUPPLEMENTAL INFORMATION DISCLOSURE CITATION IN AN APPLICATION November 29, 2004 (Use several sheets if necessary)		FIRST NAMED INVENTOR Daniel Alvarez, Jr.		FILING DATE October 10, 2003	
		EXAMINER Carrillo, Bibi S.		CONFIRMATION NO. 3090	
				GROUP 1746	

U.S. PATENT DOCUMENTS				
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	AA			
	AB			
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	AJ			
	AK			
	AA2			
	AB2			
	AC2			
	AD2			
	AE2			
	AF2			
	AG2			
	AH2			
<i>88</i>	AI2	5,230,721	07-27-1993	Ohmi
<i>62</i>	AJ2	5,938,854	08-17-1999	Roth
<i>62</i>	AK2	6,124,211	09-26-2000	Butterbaugh et al.
<i>62</i>	AA3	2002088478	07-11-2002	Degendt et al.
	AB3			
	AC3			

EXAMINER <i>Scall</i>	DATE CONSIDERED <i>2/8/05</i>
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PTO-1449 REPRODUCED  <b>SUPPLEMENTAL INFORMATION DISCLOSURE CITATION IN AN APPLICATION</b>  November 29, 2004  (Use several sheets if necessary)	ATTORNEY DOCKET NO. 3194.1026-002		APPLICATION NO. 10/683,904	
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	EXAMINER Carrillo, Bibi S.	CONFIRMATION NO. 3090	GROUP 1746	

FOREIGN PATENT DOCUMENTS					
		DOCUMENT NUMBER Country Code-Number-Kind Code (if known)	DATE MM-DD-YYYY	NAME OF PATENTEE OR APPLICANT OF CITED DOCUMENT	TRANSLATION YES NO
<i>BS</i>	AL	WO 01/37329 A1	05-25-2001	Lucent Technologies, Inc.	
<i>BS</i>	AM	EP 0 867 924 A2	09-30-1998	Interuniversitair Micro- Elektronica Centrum VZW 3001 Heverlee (BE)	
	AN	<del>DE 199 24 058 A1</del>	<del>11-30-2000</del>	<del>Robert Bosch GmbH</del>	X
	AO			<i>no relevance or translation provided</i>	
	AP			<i>∴ not considered.</i>	
	AQ				
	AL2				
	AM2				
	AN2				
	AO2				
	AP2				
	AQ2				
	AL3				
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	AO4				
	AP4				
	AQ4				

EXAMINER <i>S. Cull</i>	DATE CONSIDERED <i>2/9/05</i>
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